

## CLAIMS

What is claimed is:

- 1 1. An apparatus for remotely monitoring and developing steps in a semiconductor  
2 manufacturing process comprising:  
3 at least one remote workstation connected via a remote access link to a local  
4 workstation;  
5 a test system connected via a link to the local workstation.
- 1 2. The apparatus of claim 1, further comprising a client switch that connects a client  
2 network to at least one remote workstation.
- 1 3. The apparatus of claim 1, further comprising a host switch that connects a host  
2 network to the test system and when engaged, prevents client access to the test system.
- 1 4. The apparatus of claim 3, wherein the host switch comprises a manual switch.
- 1 5. The apparatus of claim 3, wherein the host switch comprises an ethernet switch.
- 1 6. The apparatus of claim 3, wherein the host switch comprises computer security  
2 software.
- 1 7. The apparatus of claim 1, wherein the remote access link comprises:  
2 a wide area network communication line operatively coupling the local  
3 workstation to the remote workstation.
- 1 8. The apparatus of claim 7, wherein the remote access link further comprises at  
2 least one router.





1 25. The method of claim 23, wherein the semiconductor test system comprises a test  
2 system adapted to monitor the functionality of semiconductors produced by a fabrication  
3 plant.

1 26. An apparatus for remotely monitoring and developing steps in a semiconductor  
2 manufacturing process comprising:

3 at least one remote workstation operatively connected via a Wide Area Network  
4 communication line to a local workstation;

5 a test system connected via a Local Area Network to the local workstation; and

6 a host network detachably connected by a host switch and a link to the test  
7 system.

1 27. The apparatus of claim 26, further comprising a video camera networked to the  
2 test system.